

# Xi Chen

## List of Publications by Year in descending order

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#	ARTICLE	IF	CITATIONS
1	Large-Area High Aspect Ratio Plasmonic Interference Lithography Utilizing a Single High- $k$ Mode. ACS Nano, 2016, 10, 4039-4045.	7.3	58
2	High-Performance Large-Scale Flexible Optoelectronics Using Ultrathin Silver Films with Tunable Properties. ACS Applied Materials & Interfaces, 2019, 11, 27216-27225.	4.0	47
3	Efficient Thermal-Light Interconversions Based on Optical Topological Transition in the Metal-Dielectric Multilayered Metamaterials. Advanced Materials, 2016, 28, 3017-3023.	11.1	38
4	Plasmonic Lithography Utilizing Epsilon Near Zero Hyperbolic Metamaterial. ACS Nano, 2017, 11, 9863-9868.	7.3	33
5	Achieving pattern uniformity in plasmonic lithography by spatial frequency selection. Nanophotonics, 2018, 7, 277-286.	2.9	27
6	Robust Extraction of Hyperbolic Metamaterial Permittivity Using Total Internal Reflection Ellipsometry. ACS Photonics, 2018, 5, 2234-2242.	3.2	25
7	Period reduction lithography in normal UV range with surface plasmon polaritons interference and hyperbolic metamaterial multilayer structure. Applied Physics Express, 2015, 8, 062004.	1.1	15
8	Super-resolution photolithography using dielectric photonic crystal. Optics Letters, 2019, 44, 1182.	1.7	6
9	Surface-Emitting Surface Plasmon Polariton Laser in a Second-Order Distributed Feedback Defect Cavity. ACS Photonics, 2019, 6, 612-619.	3.2	4
10	Plasmonic roller lithography. Nanotechnology, 2019, 30, 105202.	1.3	3
11	Performance analyses of plasmonic lithography. Proceedings of SPIE, 2017, , .	0.8	1